

AMENDMENTS TO THE SPECIFICATION:

Please replace the paragraph beginning at page 5, line 12, with the following rewritten paragraph:

--The method according to the present invention is particularly suited for the manufacturing of micro mirror Spatial Light Modulators. However, it would be applicable to a wide variety of thermal and non thermal detector devices, such as, but not limited to, quantum well detectors, pyroelectric detectors, bolometers, etc. It is particularly suitable when for some reason it is not possible to process/pattern/deposit a structure (e.g. a micro mirror array) directly on a substrate, where another structure (e.g. steering electronics) is present. This can e.g. be the case if the structure provided on said substrate is temperature sensitive to the process temperature for the processing of the structure to be provided thereon, or when the substrate is polycrystalline and the elements that are grown on top of the substrate must be ~~monocrystalline~~ monocrystalline. --

Please replace the paragraph beginning at page 8, line 27, and bridging page 9, with the following rewritten paragraph:

--Thereafter an optional metallization step is performed. If the optical properties of the material used in the component or components 120 is not good enough another material with better optical characteristics can be arranged on said free

surface of said component or components 120. The ~~arrangement~~
arrangement of said material may for instance be performed by
using sputtering; plating; Chemical Vapor Deposition; or similar
methods well known for a man skilled in the art. A material with
good optical characteristics is ~~aluminium~~ aluminum, at least from
the point of view of reflectivity.--

Please replace the paragraph beginning at page 9, line
9, with the following rewritten paragraph:

--The pattern may for instance be the micro mirror
array, a part of which 400 is shown in figure 7a, which is
characterized by individually movable reflecting elements 170,
see figure 7a and 7b. Attached to said mirror elements are
torsion or flexible elements ~~[[180]]~~ in the form of hinges. When
applying a first voltage on the electrode 220 and a second
voltage on the reflecting element 170 the potential difference
will create ~~[[a]]~~ an electrostatical attraction force which will
bend/move the reflecting element in a desired way.--